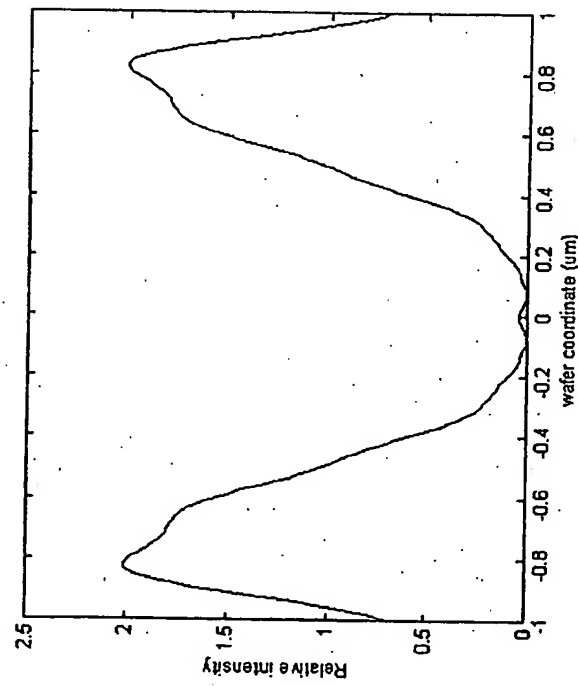


FIG. 1

Intensity at the wafer



Intensity at the CCD with
0.6 N.A. imaging system

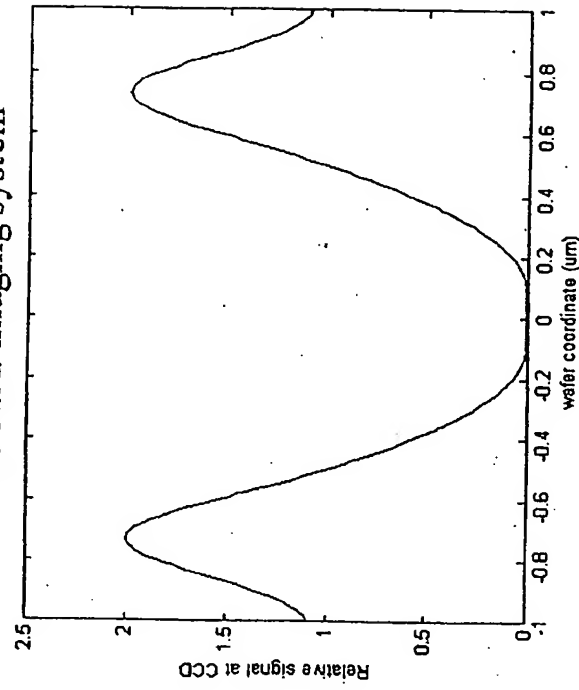


FIG. 2A

FIG. 2B

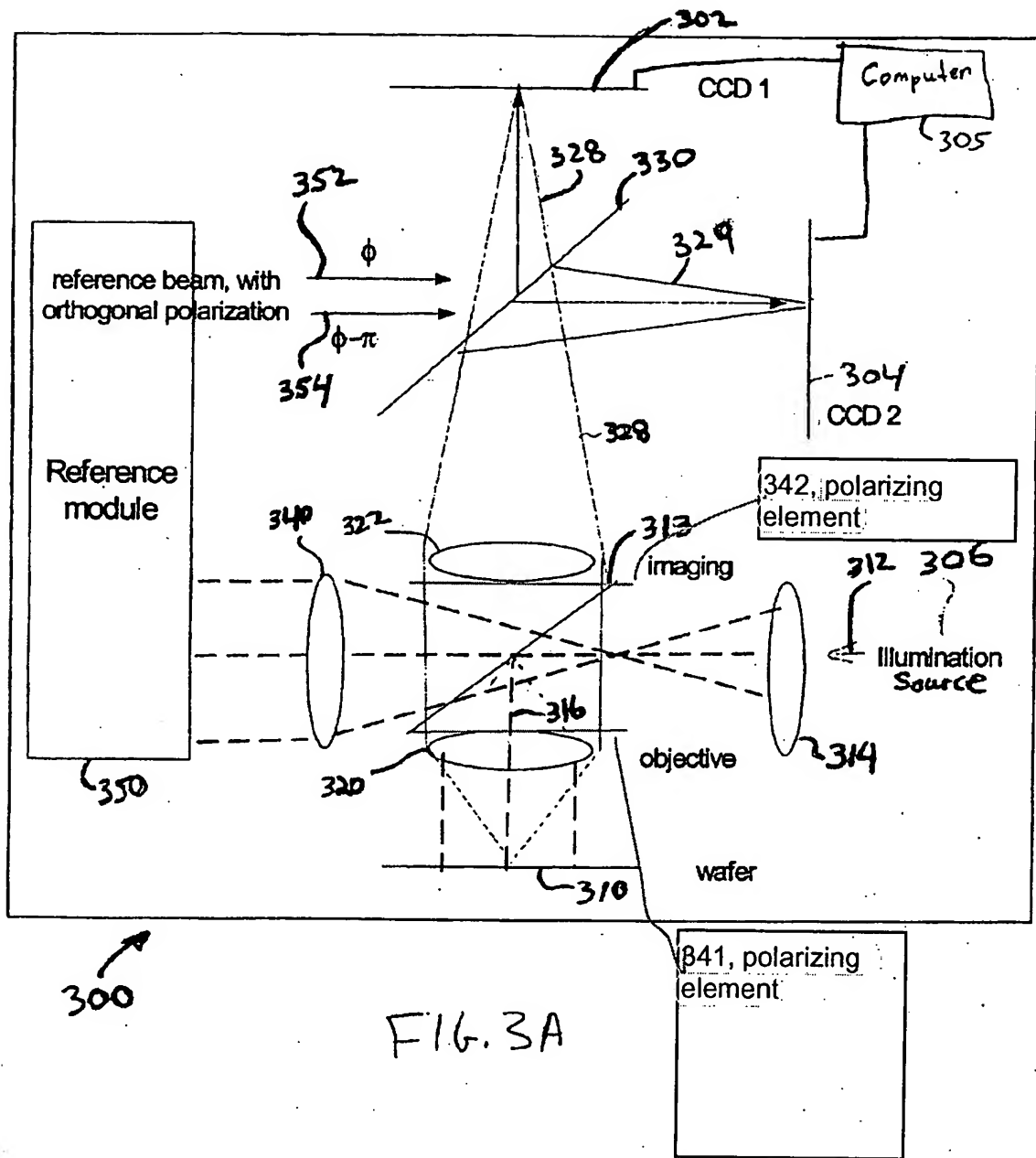


FIG. 3A

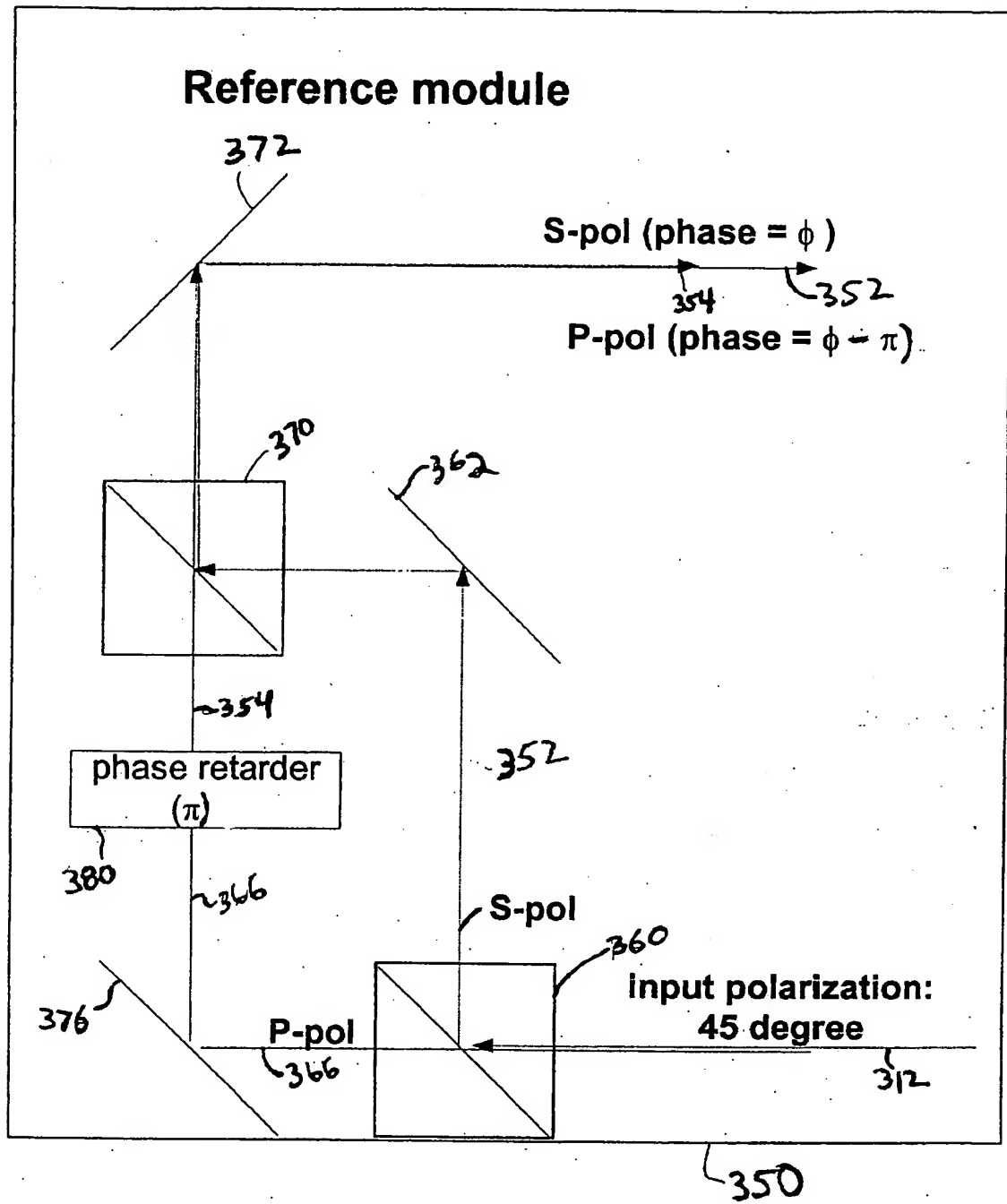


FIG. 3B

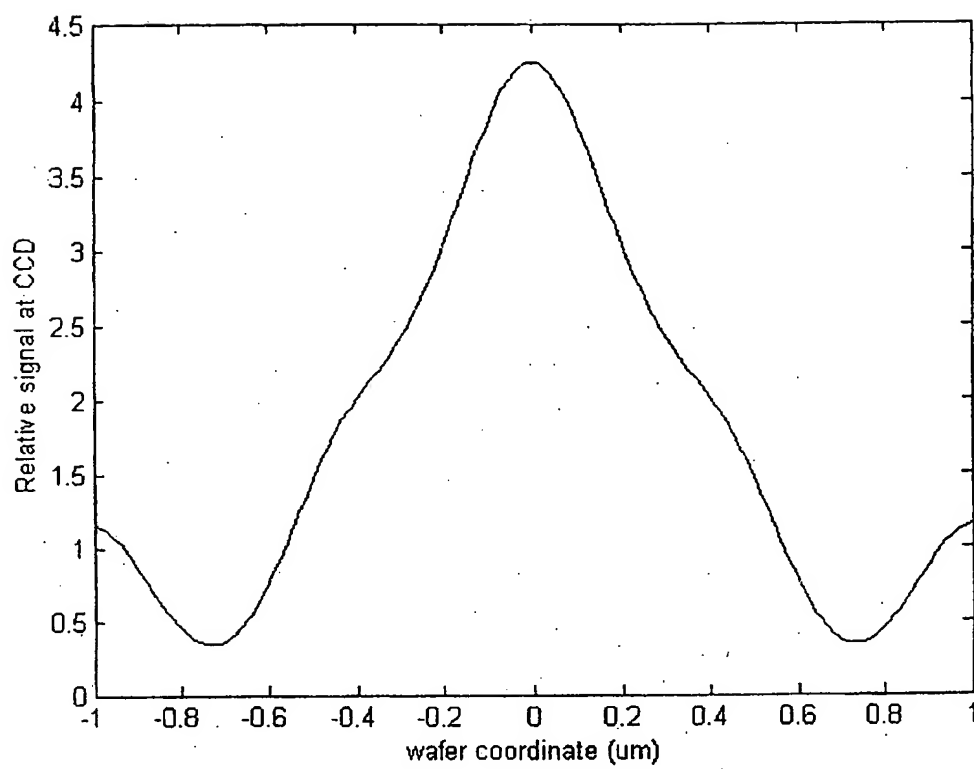


FIG. 4

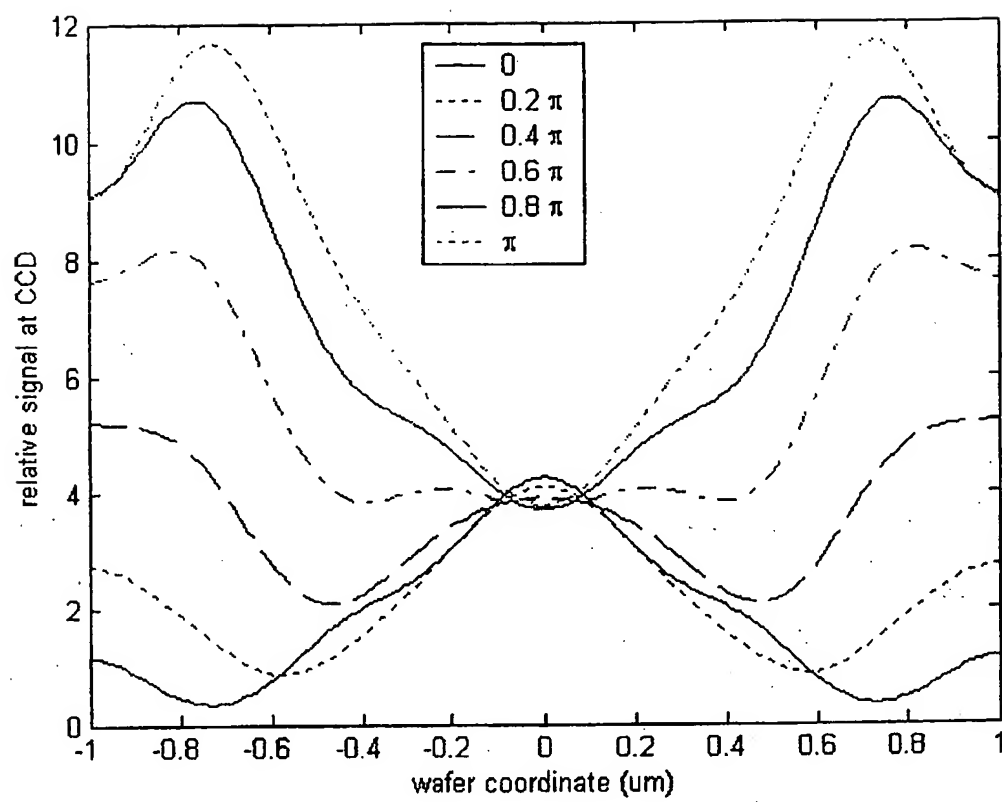


FIG. 5

FIG. 6A

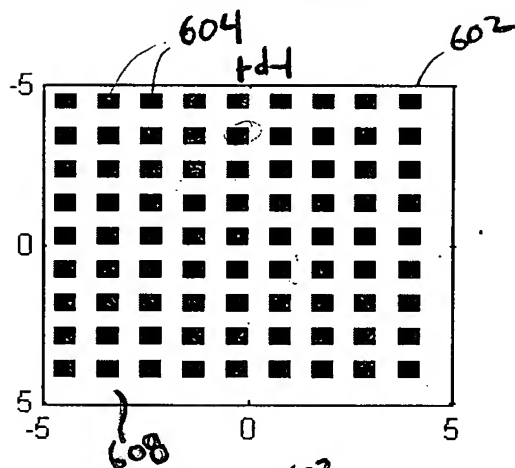


FIG. 6B

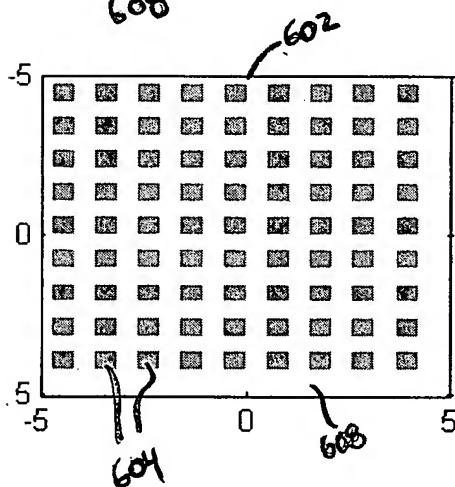
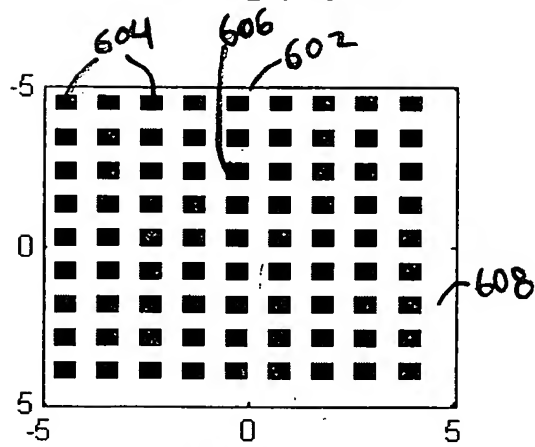


FIG. 6C

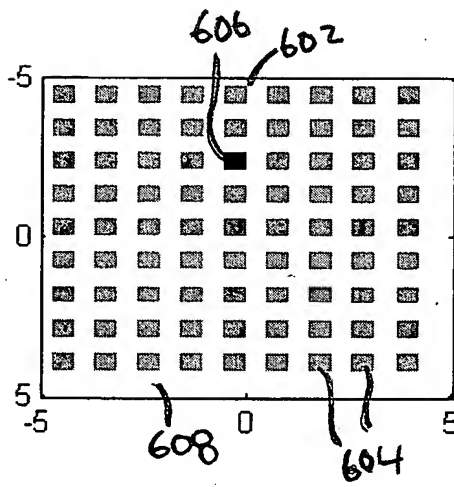


FIG. 6D

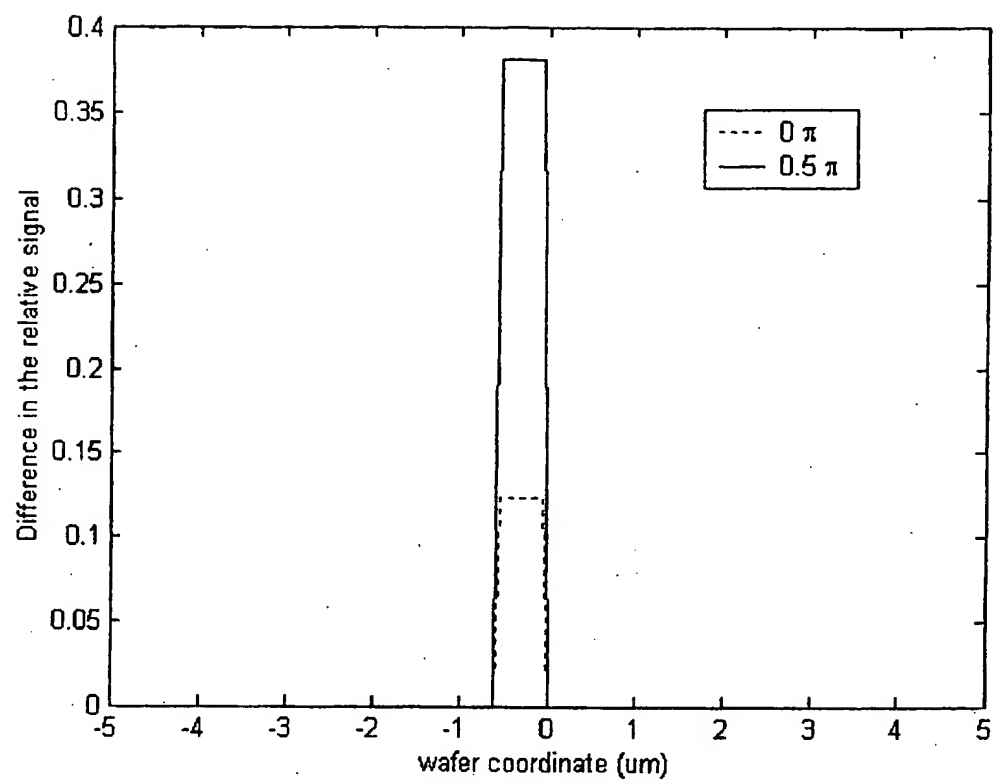


FIG. 7

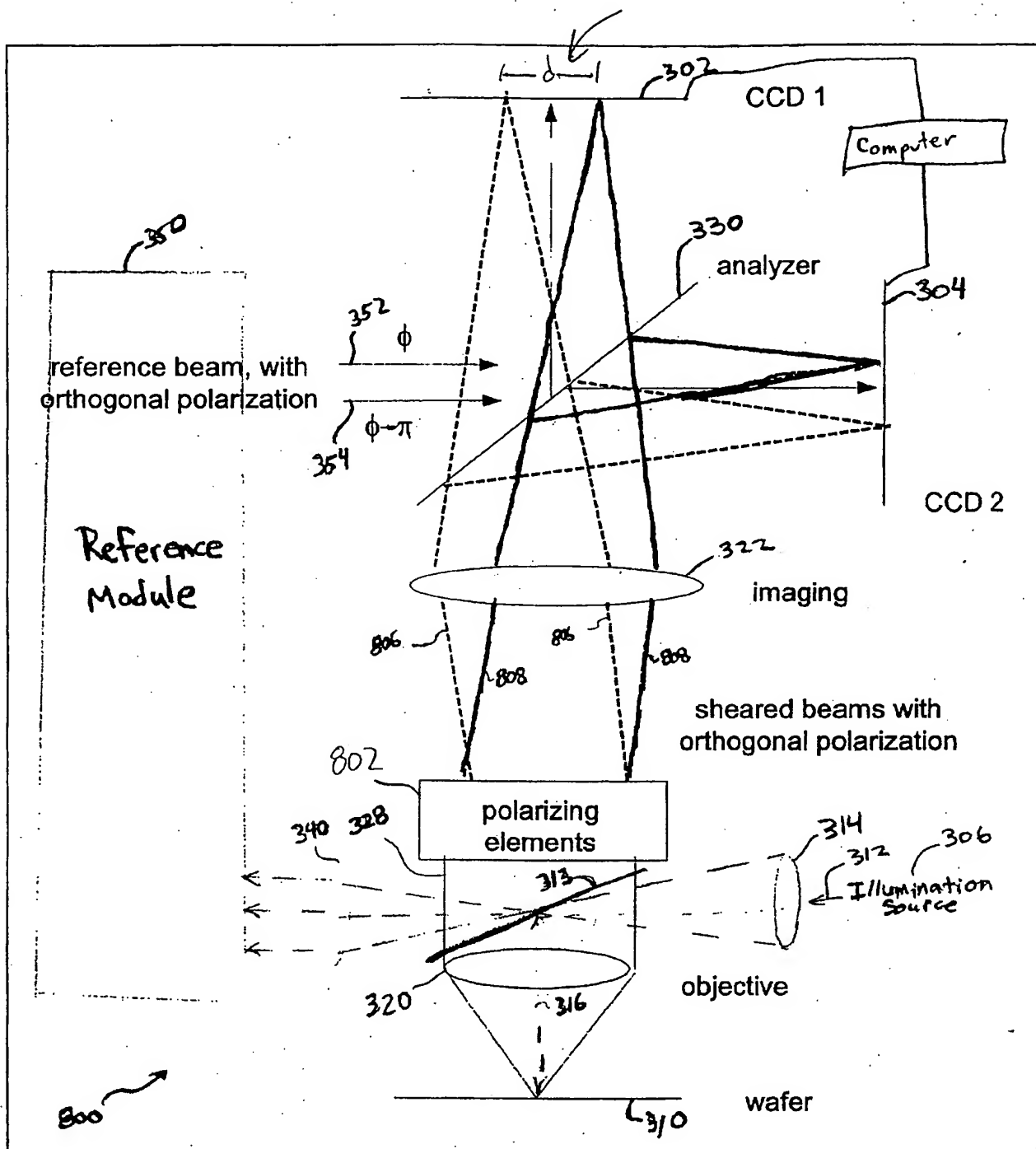
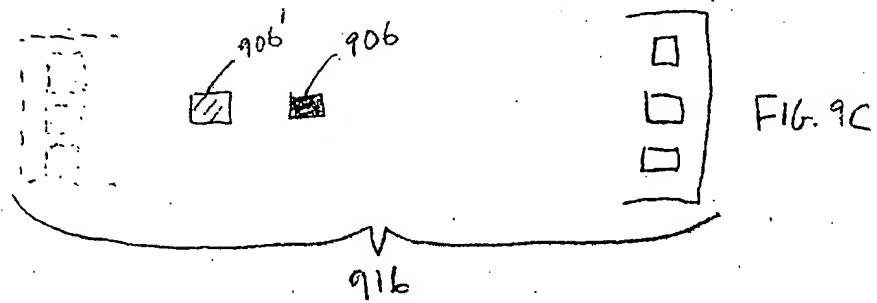
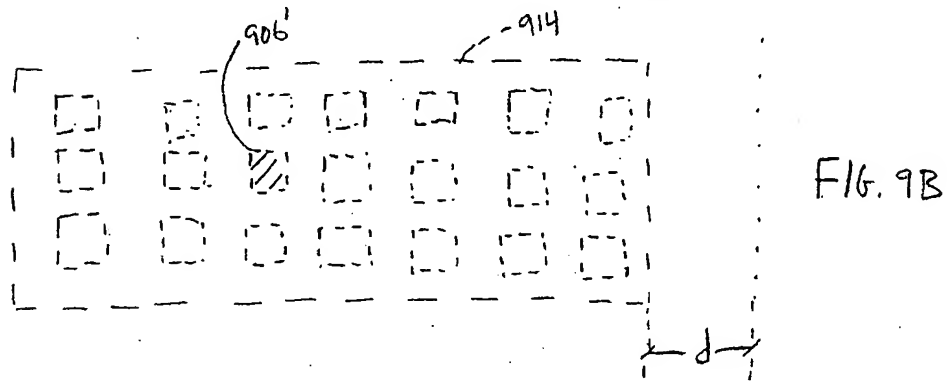
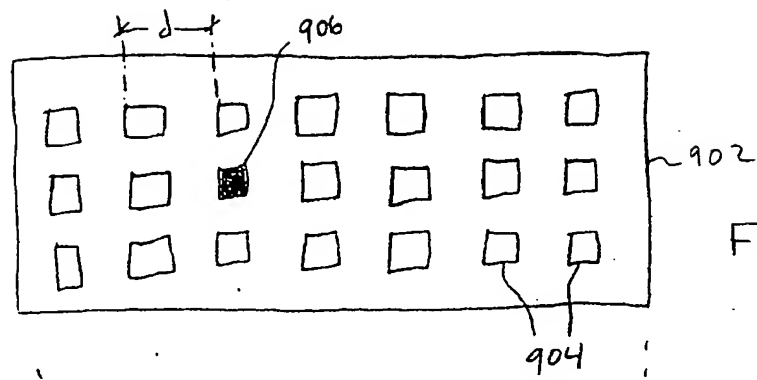


FIG. 8



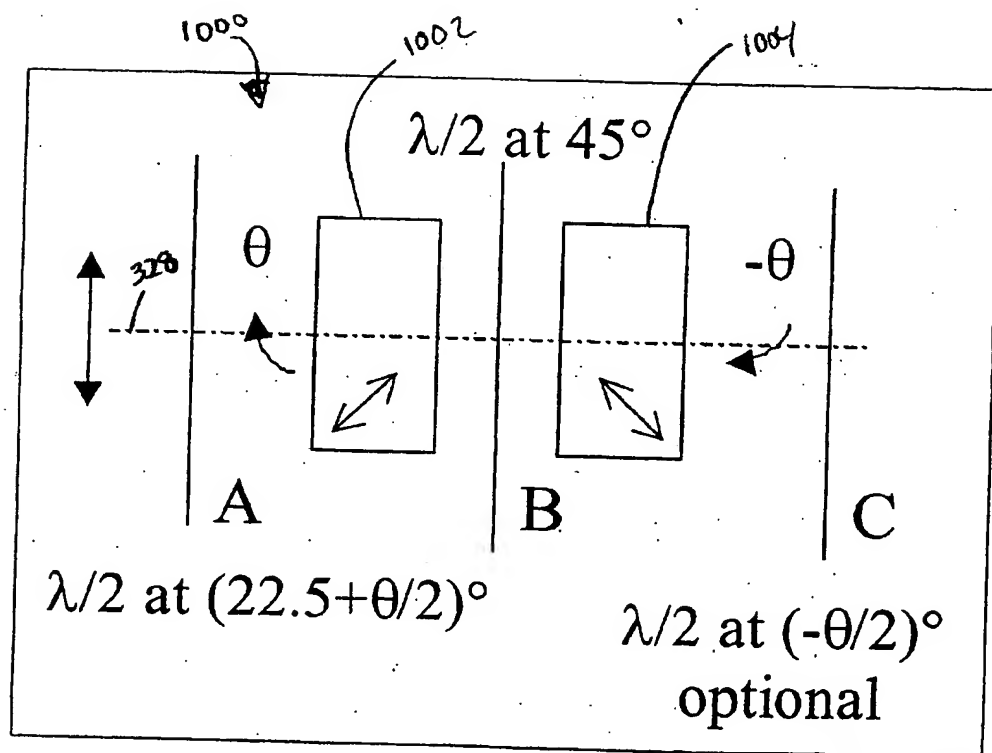
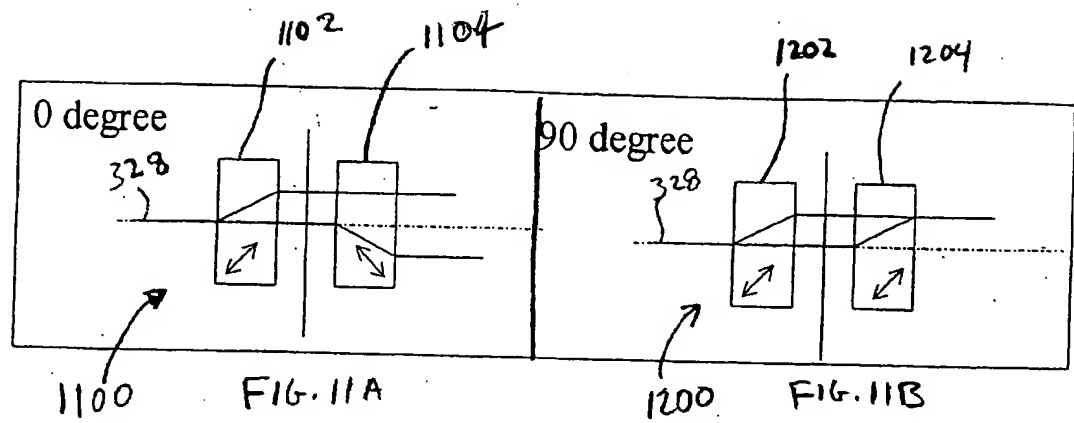


FIG. 10

FIG. 12A

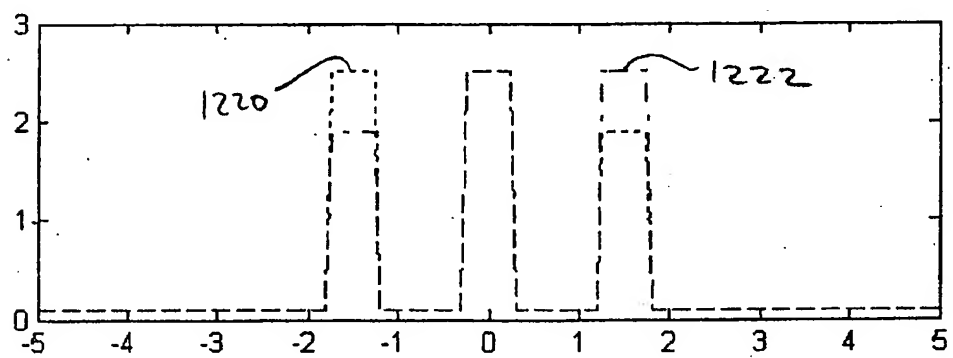
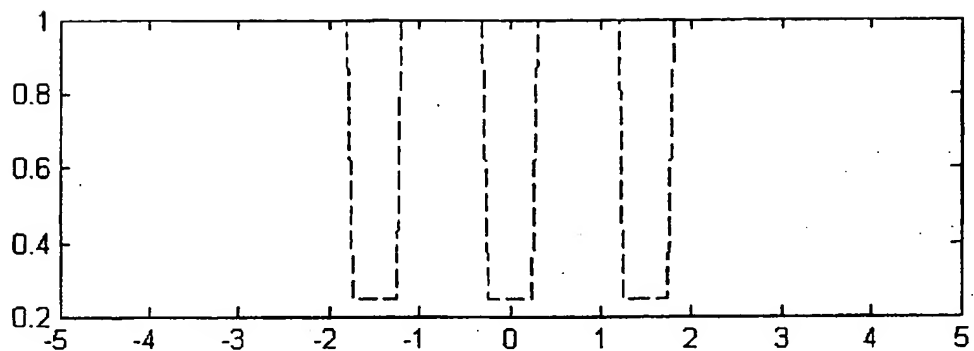


FIG. 12B

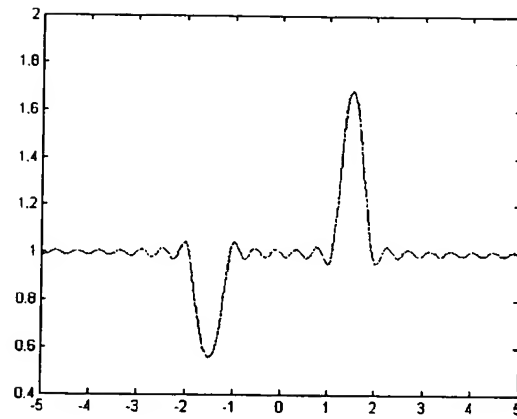


Figure 12C. The simulated signal plot at the CCD through differential interference detection. The object in is simulation is illustrated in Figure 7.

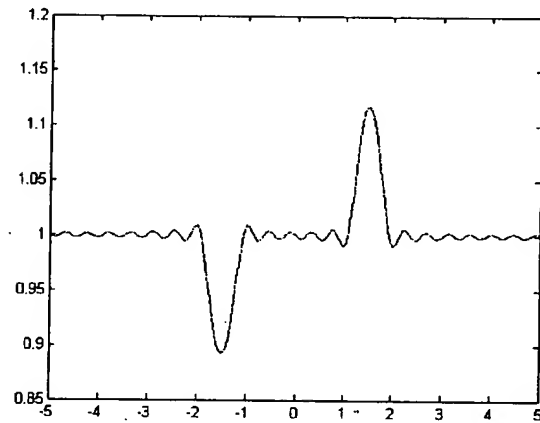


Figure 12D. The simulated signal for the high aspect ratio object with 0.1 amplitude ratio.